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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



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Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc.
Group Art Unit 1746
Examiner Shamim Ahmed
Attorney's Docket No. MI22-1106
Title: Plasma Etching Process

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

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The attached Form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included herewith. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated:

June 2, 2003

By:

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